

Docket No. 198322US-2 CONT

IN RE APPLICATION OF: TAKAHIRO HORIKOSHI ET AL

SERIAL NO: 09/680,513

RCE FILED: MAY 3, 2002

FOR: EXPOSURE METHOD, EXPOSURE APPARATUS...



ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

Transmitted herewith is an amendment in the above-identified application.

- No additional fee is required
- Small entity status of this application under 37 C.F.R. § 1.9 and § 1.27 is claimed.
- Additional documents filed herewith: Marked-Up Copy of Amendment, Request for Extension of Time

The Fee has been calculated as shown below:

CLAIMS	CLAIMS REMAINING		HIGHEST NUMBER PREVIOUSLY PAID	NO. EXTRA CLAIMS	RATE	CALCULATIONS
TOTAL	64	MINUS	58	6	× \$18 =	\$108.00
INDEPENDENT	11	MINUS	12	0	× \$84 =	\$0.00
		<input type="checkbox"/> MULTIPLE DEPENDENT CLAIMS		+ \$280 =		\$0.00
						TOTAL OF ABOVE CALCULATIONS \$108.00
		<input type="checkbox"/> Reduction by 50% for filing by Small Entity				\$0.00
		<input type="checkbox"/> Recordation of Assignment		+ \$40 =		\$0.00
						TOTAL \$108.00

- A check in the amount of \$1,028.00 is attached.
- Please charge any additional Fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.
- If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. § 1.136, and any additional fees required under 37 C.F.R. § 1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

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198322US-2 CONT



IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF:

TAKAHIRO HORIKOSHI ET AL. : GROUP ART UNIT: 2851

SERIAL NO: 09/680,513 :

RCE FILED: MAY 3, 2002 : EXAMINER: BROWN, K.

FOR: EXPOSURE METHOD, EXPOSURE APPARATUS AND MAKING METHOD OF THE APPARATUS, AND DEVICE AND MANUFACTURING METHOD OF THE DEVICE

AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

In response to the Office Action of May 17, 2002, please amend the above-identified application as follows:

IN THE CLAIMS

Please cancel Claims 22 and 53 without prejudice.

Please amend Claims 1, 4-6, 14, 16, 23, 24, 42, and 46 to read as follows:<sup>1</sup>

1. (Thrice Amended) An exposure method to transfer a pattern of a mask illuminated with exposure light from a light source onto a substrate through an optical system, said method comprising:

setting a time interval for measurement of a transmittance of said optical system;

<sup>1</sup> A marked-up copy of the amendments is attached hereto.

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